

Aalto University School of Electrical Engineering

Department of Micro and Nanosciences

Integrated RF circuits Spring 2023

Kari Stadius, Saeed Naghavi, Kimi Jokiniemi

RF IC Technologies and Devices

Brief review on RF IC technologies

- MOS technology
- Passive devices
- Bonding
- Self-learning assignment 2

Exercises & Homework

- CAD exercise
- Homeworks

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RF IC Technologies

Gallium Arsenide

- MESFET
- HEMT
- HBT

GaAs technologies have no or poor p-type FETs \rightarrow no complementary devices \rightarrow no good digital logic

Silicon / SiGe

- BJT
- BiCMOS
- CMOS

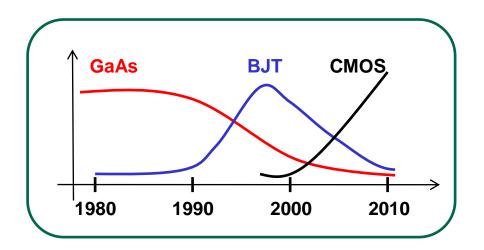
Technologies for very high speed or power

- InP
- GaN
- SiC

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RF IC designing has and will change ...



Trends:

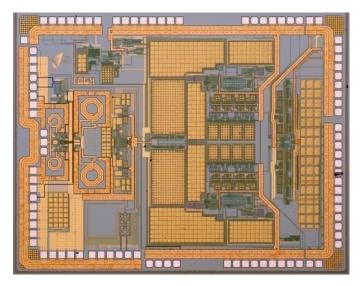
- Technology
 - GaAs → Si BJT → BiCMOS → bulk CMOS → FD-SOI & Finfet CMOS
- Design complexity
 - Circuit \rightarrow Block \rightarrow RX-TX-SX \rightarrow multi-system, SOC, SDR
- Design paradigm:
 - RF engineering \rightarrow RF IC design \rightarrow Multi-mode design
- Designers
 - Spesialists \rightarrow in-house groups \rightarrow fabless & foundry groups



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Typical RF CMOS Process

- Gate lenght: 65 nm \rightarrow 40 nm \rightarrow **28 nm** \rightarrow 14 nm \rightarrow 10 nm \rightarrow 7...5 ... 3 nm
- Typical device f_t 100-300 GHz
- 6-10 metal layers (copper or aluminium)
- NMOS & PMOS devices
 - 2-3 threshold voltage (V_T) levels
 - Specific RF devices = RF model & layout
 - Core devices simpler (model & layout)
- Passive devices <u>with</u> RF model
 - Inductors and transformers
 - Capacitors (MIM)
 - Varactors (MOS & pn)
 - Resistors (poly-silicon, 2-3 different R_{sq})
- Digital cell libraries (VHDL \rightarrow compiler)

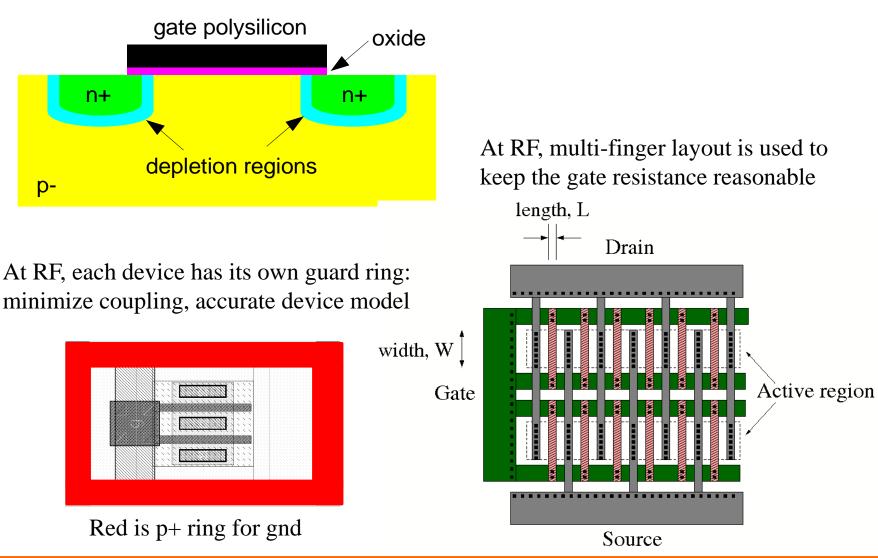


Modern CMOS technology is very versatile and good for RF ICs. Critical practical challenge is the quality (and availability) of device **MODELS.**



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NMOS Device

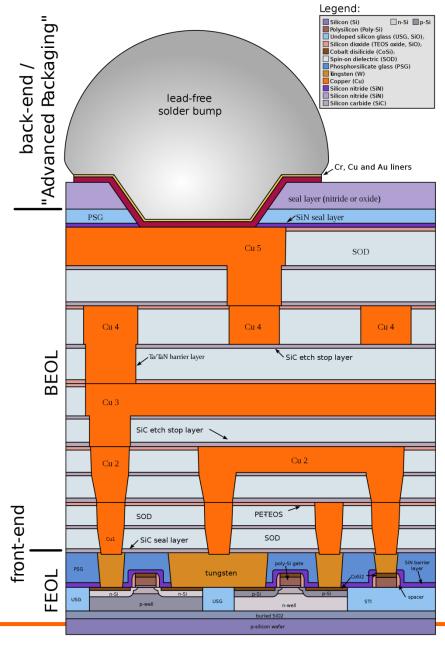




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CMOS Cross-Section



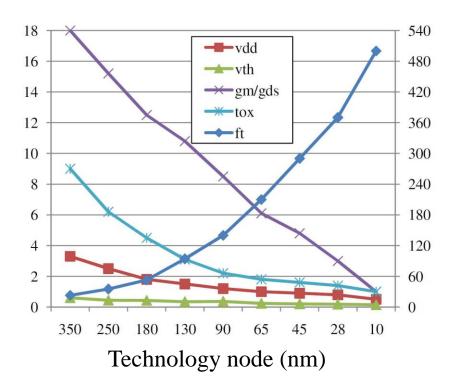
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CMOS Scaling: Analog performance is declining



CMOS evolution has resulted in

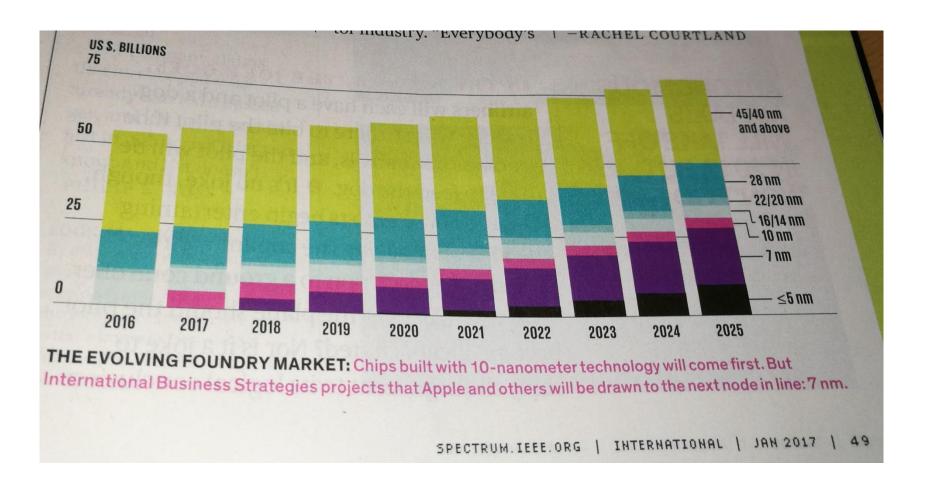
- increased integration density
- higher speed
- low supply voltage \rightarrow low power
- reduced signal headroom
- declined analog performance
 - Intrinsic gain gm/gds declines
 - Output impedance is low
 - = good switch, poor amplifier

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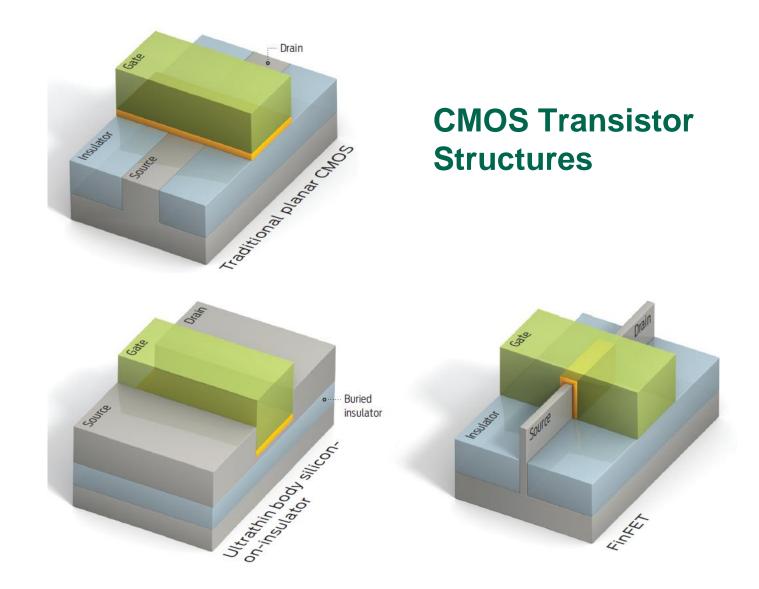
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Moore's law has hold well



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Ahmed, K.; Schuegraf, K.; "Transistor wars," IEEE Spectrum, vol. 48, no.11, pp.50-66, Nov 2011



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FD-SOI and FinFET Technologies

A video on FD-SOI by ST Microelectronics

https://www.youtube.com/watch?v=uvV7jcpQ7UY

A video on FinFET by ThresholdSystems

https://www.youtube.com/watch?v=c-3p8moNXfI&t=0s

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Passive Devices in RF CMOS process

- 1. Resistor
- 2. Inductor
- 3. Transmission line
- 4. Capacitor
- 5. MOS varactor
- 6. SC network
- 7. Bonding pad
- 8. Wire bonding
- 9. Flip-chip (BGA)

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Quality Factor Q

Quality factor Q is a metric to describe the losses of reactive component BUT, it is also used in filter design to define the steepness of your filter \rightarrow A risk to a confusion.

- Q=10, low-quality passive such as on-chip coil
- Q=100, already close to ideal in most cases
- Q>1000, losses play role only in special cases



Quality Factor Q

The most general definition of the Q-factor is based on the ratio of stored energy to dissipated energy per cycle:

$$Q = \frac{E_{store}}{E_{diss} / \omega}$$

For an ideal inductor with a series resistor R, we have

$$Q = \omega \frac{\frac{1}{2}Li^2}{\frac{1}{2}Ri^2} = \frac{\omega L}{R}$$

Alternative definition is based on 3-dB bandwidth of a resonator / filter

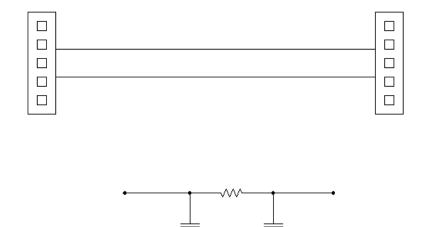
$$Q_{3dB} = \frac{\omega_0}{\Delta \omega_{3dB}}$$

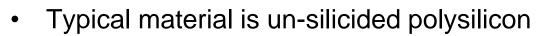
Now, consider an ideal (lossless) LC-bandpass filter: Q is infinite, Q_{3dB} is real.

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Integrated Resistor





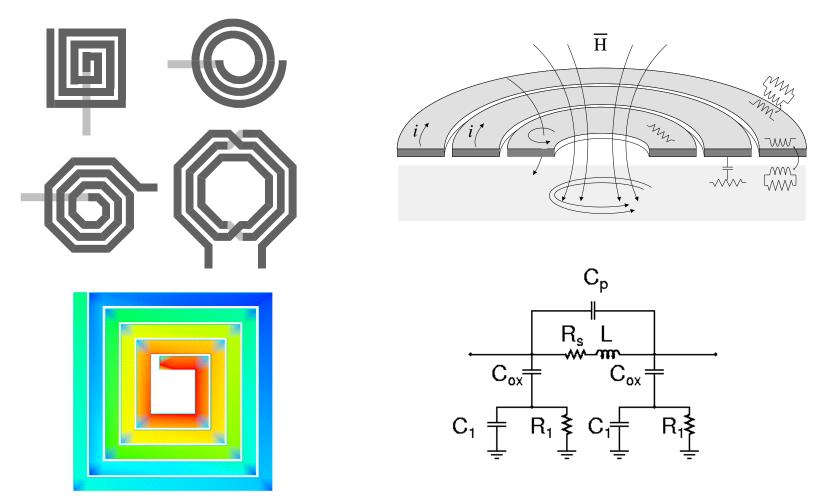
- Sheet resistance typ. 100-300 Ω
- Quite small parasitic capacitance, OK for RF ICs
- Process variation significant, typ. 20-50 %
- "well"-type silicon resistors not good for RF; High Cpar



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Monolithic Inductor

Very important for RF ICs \rightarrow Self-learning assignment



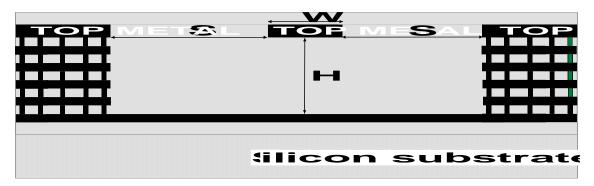


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Integrated Transmission Line

Microstrip line $h \ll s$

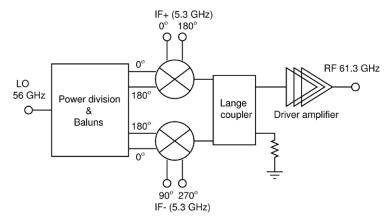


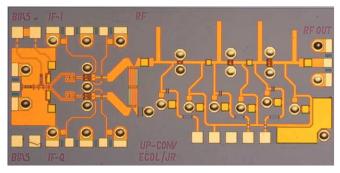
Coplanar waveguide (CPW)

TOPMETS	L TOP MESAL	TOP
i ni mi mi mi mi		
ilicon substrate		



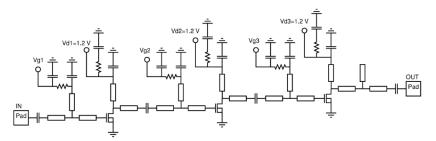
Examples of Transmission Line Circuits

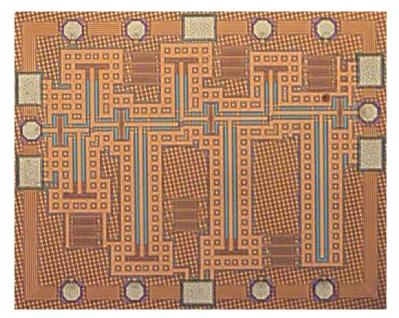




@ Jan Riska

A 60-GHz three stage amplifier





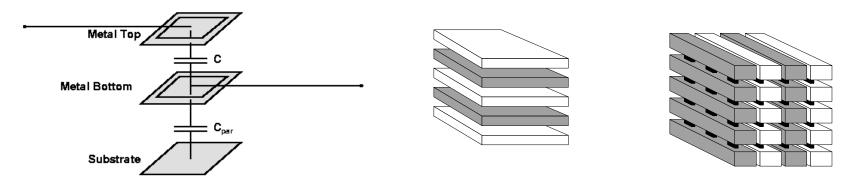
@ Mikko Varonen



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Integrated Capacitors



Metal-insulator-metal (MIM)

Sandwich MIM

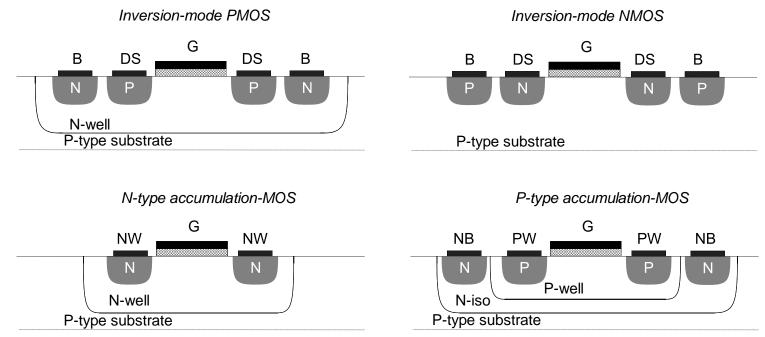
Lateral flux

- Main issues are capacitance density and C/Cpar
- Quality factors are high; take care of interconnections
- In sub-100nm technologies lateral flux caps are better
- Process variation significant, typ. 10-30 %



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MOS varactors

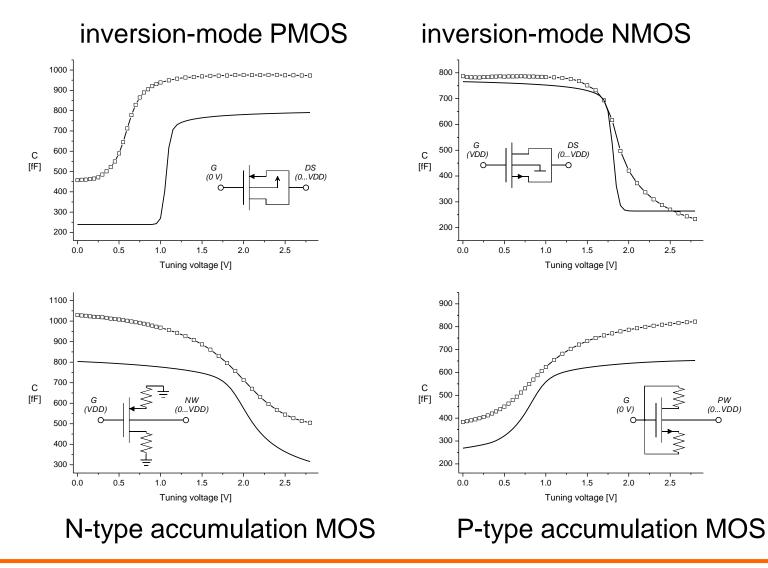


- Four types are available, inversion-mode are "ordinary" MOSFETs
- Quality factor and tuning range (Cmax/Cmin) are competing properties
- Typ. Q~50 at 2 GHz and Cmax/Cmin ~3
- Process variation tracks to MOSFET variation

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MOS Varactors

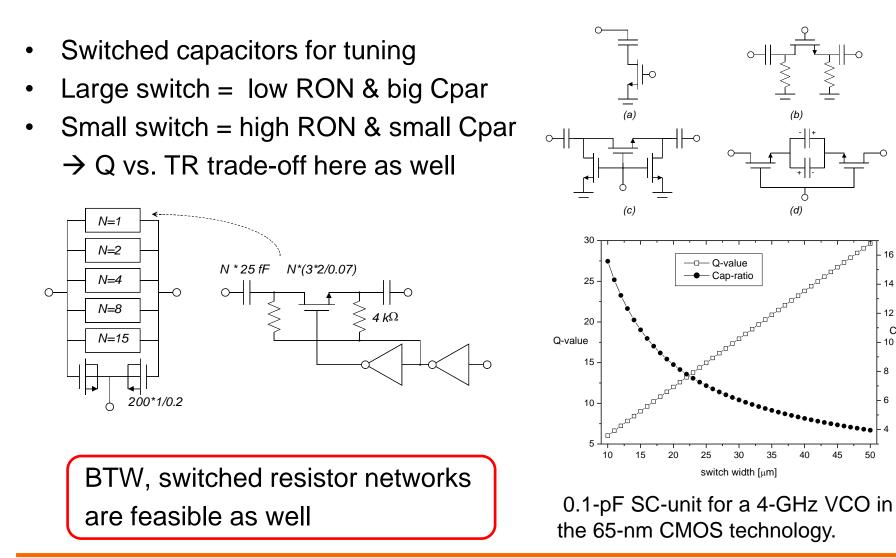


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Switched-Capacitor Network



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16

14

12

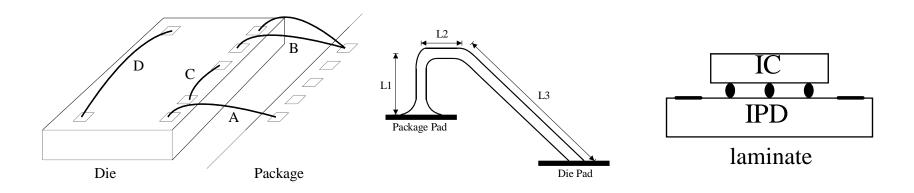
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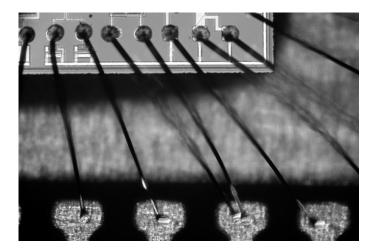
8

50

C/Coff

Wire Bonding and Flip-Chip Assembly



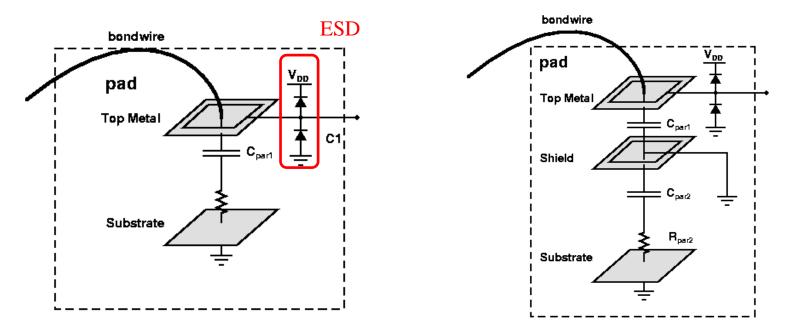


- Bond wire = high-Q inductor, L=1nH / mm, typ. 1-3 mm
- Ball-grid array solder bumb H=100-200 um, Ø~50 um small high-Q inductor
- Flip-chip requires substrate (laminate) and second bonding → modeling !



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Bonding Pad



- Pad produces parasitic capacitance
- ESD protection circuit produces a large parasitic capacitance
- "RF pad" model needed in a design kit



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Recap

RFIC technologies

- CMOS is the prevalent tech best for mixed mode apps
- SiGe BiCMOS for mmWave applications
- GaN for power amplifiers
- InP for very high frequencies

RFIC components

- Model availability / accuracy is the key question
- Coils are a specialty of RF ICs
- Transmission lines appear at above 50 GHz



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Next Meeting

Topics will be

- concepts related to amplifiers
- low-noise amplifiers
- power amplifiers
- buffers

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Self-Learning Assignment 2

Objectives are to familiarize yourself with properties of **monolithic coils** and transformers



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Session continues at 14:15

Introduction & guidance on homeworks and CAD exercises.



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